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Heeyeop CHAE received his B.S. and M.S. in chemical engineering from Seoul National University, and his Ph.D. in chemical engineering from Massachusetts Institute of Technology. After his Ph.D. he joined Applied Materials, a semiconductor equipment company, in California, USA as a senior process engineer for 4 years. He has been working as a professor in the School of Chemical Engineering at Sungkyunkwan University (SKKU) since 2004. He is a vice president of Korean Vacuum Society and an active member of American Vacuum Society. His research interests include i) plasma enhanced atomic layer etching and deposition, ii) low global warming etching gas development, iii) plasma monitoring and machine learning and iv) light emitting quantum dot materials and devices.